

Notice of References Cited	Application/Control No. 10/711,145	Applicant(s)/Patent Under Reexamination CHEN ET AL.	
	Examiner Phillip S. Green	Art Unit 2823	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,479,391 B2	11-2002	Morrow et al.	438/706
*	B	US-6,660,627 B2	12-2003	Hu et al.	438/624
*	C	US-6,872,666 B2	03-2005	Morrow, Patrick	438/700
	D	US-			
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	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	L.P. Allen et al., Substrate Smoothing Using Gas Cluster Ion Beam Processing, 2001, Journal of Electronic Materials, Vol. 30, No. 7. (Abstract only)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.